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U.S.S.N. 10/677,155

**DEC 29 2006**

**IN THE CLAIMS**

Please cancel Claims 6,13 and 18 without prejudice.

Please amend Claims 1,7-9,14-16.

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Listing of Claims

1. (currently amended) An apparatus for electrically testing a microelectronic product while moveably applying an electrical stress comprising:

an electrical test head to which is mated a microelectronic product for electrically testing the microelectronic product; and

a movable electrical probe tip separately positionable from said electrical test head during electrical testing such as to electrically stress a portion of the microelectronic product other than an electrical contact portion of the microelectronic product while said electrical test head is simultaneously positionable to electrically contact said electrical contact portion to produce electrical test data for said microelectronic product; and

a radiation beam source positioned with respect to the electrical probe tip such as to simultaneously radiation stress the portion of the microelectronic product other than the electrical contact portion of the microelectronic product.

2. (original) The apparatus of claim 1 wherein the

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microelectronic product is a semiconductor product.

3. (original) The apparatus of claim 1 wherein the microelectronic product is a ceramic substrate product.

4. (original) The apparatus of claim 1 wherein the microelectronic product is an optoelectronic product.

5. (previously presented) The apparatus of claim 1 further comprising a controller which:

controls the electrical probe tip positioning and biasing with respect to the portion of the microelectronic product other than the electrical contact portion of the microelectronic product; and

simultaneously collects said electrical test data from the electrical test head.

6. (cancelled)

7. (currently amended) The apparatus of claim ~~6~~ 1 wherein the electrical probe tip and the radiation beam source are on the same side of the microelectronic product.

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8. (currently amended) The apparatus of claim 6 1 wherein the electrical probe tip and the radiation beam source are on opposite sides of the microelectronic product.

9. (currently amended) A method for electrically testing a microelectronic product while moveably applying an electrical stress comprising:

providing an electrical test apparatus comprising:

an electrical test head to which is mated a microelectronic product for electrically testing the microelectronic product; and

a movable electrical probe tip separately positionable from said electrical test head during electrical testing such as to electrically stress a portion of the microelectronic product other than an electrical contact portion of the microelectronic product while said electrical test head is simultaneously positionable to electrically contact said electrical contact portion to produce electrical test data for said microelectronic product; and

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sequentially movably positioning the electrical probe tip to sequential positions comprising said other than an electrical contact portion of the semiconductor product and electrically stressing the microelectronic product with said electrical probe tip while simultaneously electrically testing the microelectronic product with said electrical test head electrically contacting said electrical contact portion to produce said electrical test data for said microelectronic product- ;and

providing a radiation beam source positioned with respect to the electrical probe tip such as to simultaneously radiation stress the portion of the microelectronic product other than the electrical contact portion of the microelectronic product.

10. (original) The method of claim 9 wherein the microelectronic product is a selected from the group consisting of a semiconductor product and a ceramic substrate product.

11. (original) The method of claim 9 wherein the microelectronic product is an optoelectronic product.

12. (previously presented) The method of claim 9 further comprising providing a controller which:

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controls the electrical probe tip positioning and biasing with respect to the portion of the microelectronic product other than the electrical contact portion of the microelectronic product; and

simultaneously collects said electrical test data from the electrical test head.

13. (cancelled)

14. (currently amended) The method of claim ~~13~~ 9 wherein the electrical probe tip and the radiation beam source are on the same side of the microelectronic product.

15. (currently amended) The method of claim ~~13~~ 9 wherein the electrical probe tip and the radiation beam source are on opposite sides of the microelectronic product.

16. (currently amended) A method for electrically testing a semiconductor product while moveably applying an electrical stress comprising:

providing an electrical test apparatus comprising:

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an electrical test head to which is mated a semiconductor product for electrically testing the semiconductor product; and

a movable electrical probe tip separately positionable from said electrical test head during electrical testing such as to electrically stress a portion of the semiconductor product other than an electrical contact portion of the semiconductor product while said electrical test head is simultaneously positionable to electrically contact said electrical contact portion to produce electrical test data for said semiconductor product; and

sequentially movably positioning the electrical probe tip to sequential positions comprising said other than an electrical contact portion of the semiconductor product and electrically stressing the semiconductor product with said electrical probe tip while simultaneously electrically testing the semiconductor product with said electrical test head electrically contacting said electrical contact portion to produce said electrical test data for said semiconductor product; and

providing a radiation beam source positioned with respect to the electrical probe tip such as to simultaneously radiation stress the portion of the semiconductor product other than the electrical contact portion of the semiconductor product.

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17. (previously presented) The method of claim 16 further comprising providing a controller which:

controls the electrical probe tip positioning and biasing with respect to the portion of the semiconductor product other than the electrical contact portion of the semiconductor product; and

simultaneously collects said electrical test data from the electrical test head.

18. (cancelled)

19. (original) The method of claim 16 wherein the electrical probe tip and the radiation beam source are on the same side of the semiconductor product.

20.. (original) The method of claim 16 wherein the electrical probe tip and the radiation beam source are on opposite sides of the semiconductor product.